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PATENT

UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Fuerhoff et al.

Serial No. 09/502,340

Filed February 10, 2000

For METHOD AND APPARATUS FOR CONTROLLING DIAMETER OF A SILICON  
CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS

April 28, 2000

TO THE COMMISSIONER OF PATENTS AND TRADEMARKS,

SIR:

**INFORMATION DISCLOSURE STATEMENT**

In accordance with 37 C.F.R. 1.97 and 1.98 and MPEP 609, and in compliance with the duty  
of disclosure set forth in 37 C.F.R. 1.56, applicants submit copies of the references listed on the  
\* attached PTO Form 1449 (modified) for consideration by the Patent and Trademark Office in the  
above-entitled application and to be made of record herein.

Respectfully submitted,

Robert M. Bain, Reg. No. 36,736  
SENNIGER, POWERS, LEAVITT & ROEDER  
One Metropolitan Square, 16th Floor  
St. Louis, Missouri 63102  
(314) 231-5400

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**CERTIFICATE OF MAILING**

I certify that this Letter to the Patent and Trademark Office and attached PTO Form 1449 is  
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day of April, 2000.

  
C. Jonell Layton, PLS

RMB/cjl  
Attachments